From Self-Assembled Monolayers to Polymer Brushes

Rainer Jordan

Chair of Macromolecular Chemistry Faculty of Chemistry and Food Chemistry School of Science



Ultrathin, Thin, and Thick(er) Films on Solid Substrates



Overview: From Self-assembled Monolayers to Polymer Brushes



R. Jordan in: Polymeric Materials in Organic Synthesis and Catalysis, (M. Buchmeiser, ed.), Wiley-VCH 2003.

PART I Self-assembled Monolayers SAMs

Definition: Self-assembled monolayers (SAMs)...

...are ordered, chemically and thermally stable two-dimensional aggregates that are formed spontaneously by the adsorption of surface active molecules onto a solid. The surface active molecule should feature:

- 1. a head group, suitable for strong interactions or even chemical bonding with the surface,
- 2. a mesogenic moiety responsible for the 2D packing and favorable lateral interactions with the next neighbors and
- 3. a tail or end group determining the properties of the newly formed solid surface. The SA of a film is a concerted interplay of various forces.

The overall stability of a SAM is determined by all inter- and intramolecular forces in the film.





- (a) Cartoon of a SAM. Shaded circle indicates adsorbed or chemisorbed head group and open circle end group, which can be chosen from variety of chemical functionalities.
 -) Schematic of different energies. ΔE_{ads} stands for adsorption energy, ΔE_{corr} corrugation (rippling) of substrate potential experienced by molecule, ΔE_{hyd} van der Waals interaction of (hydrocarbon) tails, and ΔE_g energy of gauche defect (or, generally, deviation from fully stretched backbone).

Substrate	Ligand, Precursor	Binding
Au	RSH, ArSH (thiols)	RS-Au
Au	RSSR' (disulfides)	RS-Au
Au	RSR' (sulfides)	RS-Au
Au	RSO ₂ H	RSO ₂ -Au
Au	R ₃ P	R₃P- Au
Ag	RSH, ArSH	RS-Ag
Cu	RSH, ArSH	RS-Cu
Pd	RSH, ArSH	RS-Pd
Pt	RNC	RNC-Pt
GaAs	RSH	RS-GaAs
InP	RSH	RS-InP
SiO ₂ , oxides	RSiCl ₃ , RSi(OR') ₃	siloxane
Si/Si-H	(RCOO) ₂ (neat)	R-Si
Si/Si-H	RCH=CH ₂	RCH ₂ CH ₂ Si
Si/Si-Cl	RLi, RMgX	R-Si
metal oxides	RCOOH	RCOO ⁻ MO
metal oxides	RCONHOH	RCONHOH МО
ZrO ₂	RPO ₃ H ₂	RPO ₃ ²⁻ Zr ^{IV}
In ₂ O ₃ /SnO ₂ (ITO)	RPO ₃ H ₂	RPO ₃ ²⁻ M ⁿ⁺

G.Whitesides, Y. Xia, Angew. Chem. 1998

R. Jordan, *From self-assembled monolayers to polymer brushes* Wiley-VCH 2003

Various types of SAMs – End Group // Substrate

- Acids (RCOOH, RSO₃H, RPO₃H₂) on oxide surfaces (AgO, Al₂O₃, Fe₂O₃)
- Trichlorosilanes (RSiCl₃), Trialkoxysilanes (RSi(OAlkyl)₃ on OH surfaces (SiO₂ (Si-OH), Al₂O₃, OH-substituted polymers)
- Sulfur compounds on metallic surfaces (Au, Ag, Cu, Pt, Pd) and on GaAs.



SAMs of Thiols – Experimental

In the preparation of SAMs, the substrate is immersed into a dilute (10 mM to 1 mM) solution of the desired thiol. For thiols on gold, initial adsorption is fast (seconds); then an organization phase follows which should be allowed to continue for > 15 h for best results.



Self-Assembled Monolayers grown from solution



Self-Assembled Monolayers grown from vapor



Alkanethiols – Film Formation

Evolution of structures of decanethiol on Au(111) during growth. (not all are stable equilibrium structures).

Preparation method: Adsorption from the gas phase in UHV conditions





- **Constant-current STM** scans for increasing exposures of mercaptohexanol vapor on Au(111).
- (A) clean ``herringbone" reconstructed Au(111) surface; the inset shows three stable islands nucleated between herringbone double rows after first stage of exposition.
- (B) Striped phase island (pointing finger).
- (C) Continued striped phase growth displacing herringbone elbows.
- (D) Continued striped phase growth with Au vacancy islands (pointing finger) becoming visible.
- (E) Nucleation of standing-up phase within striped phase.
- (F) Growth of standing-up phase at expense of striped phase until saturation.

From G.E. Poirier, *Langmuir* 1999.

LB-FILMS vs. SAMs

Langmuir-Blodgett Monolayers

Self-assembled Monolayers





D.K. Schwarz, Annu. Rev. 2001

Alkanethiols – Film Formation Self-Assembly 1

The SFG signal is a measure for the amount of surface bonded groups in a <u>non-centrosymmetric</u> environment:

Different time scales (including long-time effects) in solution-growth of docosanethiol (SH– $(CH_2)_{21}$ -CH₃) on Au, derived from vibrational mode intensity (detected by SFG) as function of immersion time.

1. First step is the chemisorption of sulfur head group,

i.e., signal similar to that of the previous Langmuir isotherm. (*strong increase of* v_{as})

- FAST

2. Second phase corresponds to a straightening of chains, represented by decrease of the d⁻ mode (antisymmetric CH_2 becomes invisible). CH_2 group adjacent to end group already exhibits slower ordering (represented by d_{tCH2}^+ mode; symmetric).

- 3- 4 TIMES SLOWER

3. End of chain shows slowest ordering, as evidenced by evolution of d^{+}_{tCH2} mode of end groups (increase of symmetric; CH_3 and CH_2).

- 35 - 70 TIMES SLOWER

Himmelhaus, Eisert, Buck, Grunze, J. Phys. Chem. B 2000.



SAMs from Thiols – Chemistry

A side-view of the p-bonding orbital between the SCH₃ adsorbate and the Au(111) surface in the hollow site position.

The bonding is NOT with a single gold atom, but with multiple gold atoms at the surface.

A gold atom in the second layer, directly underneath the hollow site, participates in the bonding.



SAMs from Thiols – Chemistry

Chemisorption of thiols on Au(111) give Au⁺ thiolate (RS⁻) species probably by:

$$Au_n^0 + RSH \Rightarrow \left[RS^-Au^{2+}H^-\right] Au_n \Rightarrow RS^-Au^+ \cdot Au_n + \frac{1}{2}H_2$$

- The adsorbing species is the thiolate.
- The heat of adsorption is ~28 kcal/mol.
- The homolytic surface-S bond strength is ~44 kcal/mol.
- The proton leaves as H_2 however even in 3D SAMs on nanoparticles with high surface area/mass *no* H_2 could be detected until ...

SAMs from Thiols – Chemistry H₂ found!

L. Kankate, A. Turchanin, A. Gölzhäuser,

On the release of hydrogen from the S-H groups in the formation of self-assembled monolayers of thiols. *Langmuir* **2009**, *25*, 10435-10438.



As determined by XPS, SA of thiols lead to a partial reduction of a nitro group to amine, while adsorption of the analogue disulfide compound did not show signs of reduction. The reduction of the nitro headgroups is accounted to the released H^{*}.

Alkanethiols – Stand-up Phase



A schematic model of the $(\sqrt{3}\times\sqrt{3})R30^{\circ}$ overlayer structure formed by alkanethiolate SAMs on Au(111). This structure places the thiols in S...S distance of 4.99 Å, which results in their tilt to reestablish the vdW interchain interactions. The angle can be deduced using FTIR spectroscopy.



Alkane Mesogen: Surface Reconstruction

Advancing and receding water contact angles on SAMs of HUT [HO(CH_2)₁₁SH] SAMs on Au(111)



Highly polar surfaces of SAMs of n-alkylthiols undergo surface reconstruction when exposed to air to minimize the surface free energy

S. Evans, R. Sharma, A. Ulman Langmuir 1991, 7, 156.

Various types of SAMs – Different Mesogens

In e.g. alkane thiols or silanes the ordering ('crystallization') lateral stability is provided by vdW – interactions between the methylene groups. Further stability can be introduced by e.g. dipol-dipol – interactions or $\pi\pi$ -interactions of aromatic mesogenes:



Various types of SAMs – Different Mesogens







Self-Assembled Monolayers of RIGID Biphenyl Thiols

Why **BIPHENYL**?

- Rigid system
- biphenyl is an effective mesogenic moiety for SA
- conjugated system
 - > different reactivity of thiol group
 - > different molecular dipole moment

DIFFERENT
SA
BEHAVIOR



X = 23 different functionalities: e.g. –H,-CH₃,-CF₃,-OH, -SH, -SCH₃,-F,-CI,-Br,-I,

-NO₂,-NH₂,-COCH₃,-COOR, -CN

Self-Assembled Monolayers Alkanethiols vs. Biphenylthiols



- Small hysteresis uniform layer no surface reorientation
- Linear relationship ideal mixture at the surface
- > Stable θ for weeks **no surface reconstruction**
- Higher absolute values polarizable system

Self-Assembled Monolayers Alkanethiols vs. Biphenylthiols



J. F. Kang, A. Ulman, S. Liao, R. Jordan, G. Yang, and G. Y. Liu, Langmuir, 2001, 17, 95.

Various types of SAMs – Alkylsilanes

SAM formation of tetradecyltrichlorosilane (TTS, C₁₄H₂₉SiCl₃) on silicon at 20°C and 30% relative humidity.

Contact angle:

SAM thickness:

The calculated thickness is 21.1 Å based on an all*trans* configuration. Alkyl chains are perpendicular to the surface.



A schematic description of the polysiloxane formed *in situ* at the monolayer substrate interface.

Simo

."0



Proposed Model by Silberzan et al. : P. Silberzan, L. Leger, D. Ausserre, J. J. Benattar, *Langmuir* **1991**, *7*, 1647-1651.

"The fact that the roughness is lower for silanated wafers is compatiblew ith a vision in which the layer is not linked to the surface by all the individual molecules but, rather, forms a "net" where molecules are linked to each other; this net would be bonded to the surface by only a few bonds." The equatorial Si-O bonds that can be connected either to another polysiloxane chain or to the surface

Lateral Patterning of SAMs



Mixed SAMs – Patterned SAMs : µCP



anna anna ← HDT

PDMS

nm thick; D: 200 nm thick) that were fabricated by μ CP with HDT followed by chemical etching in an aqueous solution of ferricyanide (Whitesides et al. 1998).



Comparison of STM images of SAMs of dodecanethiol (DDT) on Au(111) formed by μ CP and by adsorption from solution.

µCP: a solution of DDT in ethanol as the "ink" ; t = 10 s

Adsorption: equilibrated with a solution of DDT in ethanol for about 18 h.



LFM. The surface was printed in HDT; the remaining regions were then derivatized with $HS(CH_2)_{15}$ COOH by immersing the patterned sample in a solution containing the second thiol. Relatively high frictional forces between the probe and the surface were detected in regions covered with a COOH- terminated SAM (light), and relatively low frictional forces were measured over regions covered with a CH₃ - terminated SAM (dark).

Patterned SAMs: Scanning Probe Lithography



G.Y. Liu et al. Acc. Chem. Res. 2000

Mixed SAMs – Patterned SAMs : Chemical Lithography



AFM Images and averaged height profiles of lines that were written with a focused electron beam into a nitrobiphenylthiol monolayer. a-c) 100 nm lines after electon exposure (a) and immobilization of TFAA (b) and PFBA (c). d-f) 20 nm lines after electon exposure (d) and immobilization of TFAA (e) and PFBA (f).

exposure (10000 µC/cm² at 300 eV) through a 150 nm stencil mask.

M. Grunze et al. *Surf. Sci.* **2000** M. Grunze et al. *Adv. Mat.* **2001**

SAMs: Tailored Surfaces as Initiator Systems for Surface-Initiated Polymerization (SIP)



Thank you!

to be continued with...

PART II Polymer Brushes